Advanced Characterization Techniques for Thin Film Solar Cells

von
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Zu Inhaltsverzeichnis

Erratum
"Advanced Characterization Techniques for Thin-Film Solar Cells"
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Chapter 4:

Numbering of references was incorrect. Reference corrections are as follows:

p. 90, fig. caption right-hand column, 4 lines from bottom: [67] → [22]
p. 91, 2 lines from top: [22] → [23]; 9 lines from top: [23] → [22]; 13 lines from top: [23] → [24]; fig. caption right-hand column, 3 lines from bottom: [68, 69] → [25, 26]
p. 92, line 14 from top: [24] → [27]; bottom line: [25, 26] → [28, 29]
p. 93, 14 lines from bottom: [27] → [30]
p. 94, line 9 from bottom: [28] → [31]; line 3 from bottom: [29] → [32]
p. 95, first line: [30, 31] → [33, 34]; second line: [32] → [35]; line 8 from top: [33, 34] → [36, 37]; line 17 from bottom: [35] → [38]; third line from bottom: [36] → [39]
p. 96, 6 lines from bottom: [37] → [40]; 3 lines from bottom: [38, 39] → [41, 42]; bottom line: [40] → [43]
p. 98, 6 lines from top: [41] → [44]; 17 lines from top: [23] →[22]; 15 lines from bottom: [42] → [45]; 14 lines from bottom: [23, 43] → [22, 46]
p. 99, first line: [44] → [47]; second line from top: [45] → [48]; 17 lines from bottom [46] → [49]; 12 lines from bottom: [47, 48] → [50, 51]; 5 lines from bottom: [49] → [52]
p. 100, second line from top: [50] → [53]; 5 lines from top: [51, 52] → [54, 55]; 6 lines from top: [53] → [56]; 8 lines from top: [54] → [57]; 12 lines from top: [55] → [58]; 13 lines from bottom: [56] → [59]; 10 lines from bottom: [57-59] → [60-62]; 8 lines from bottom: [60, 61] → [63, 64]
p. 101, 15 lines from bottom: [21, 62] → [21, 65]; 6 lines from bottom: [63] → [66]; 4 lines from bottom: [64, 65] → [67, 68]
p. 120, last line before "References" start: [29, 51, 66-73] → [29, 51, 69-73]
p. 103: references 22 and 23 should be exchanged, i.e.: [22] Heath, J.T, Cohen, J.D., and Shafarman, W.N. (2004); [23] Kimerling, L.C. (1974).

Chapter 6:

p. 126, line 10 from top: $(k \geq 0) \rightarrow (n, k \geq 0)$
p. 130, line 21 from top: MgF_2 or fused silica→ MgF_2, quartz, or fused silica.
p. 132, line 3 from bottom: Eqs. (6.9) - (6.10) → Eqs. (6.9) - (6.11)
p. 137, Caption of Fig. 6.4, Left column, lines 1-2: for a Si:H i-layers →for Si:H i-layers
p. 138, line 18 from top of text: transition occurs at a thickness of 200 nm → transition occurs at a thickness of 20 nm,
p. 139, line 7 from top of text : are generally slower → are generally lower
p. 149 Reference 55, line 3: dielectric function of semiconductors in → dielectric function of semiconductors, in

Chapter 9:

Figures 9.11 (p. 214), 9.12 (p. 215), 9.13 (p. 216), 9.18 (p. 221), and 9.20 (p. 224) were incorrect in the printed text – the correct versions of the figures can be found here:

Fig. 9.11

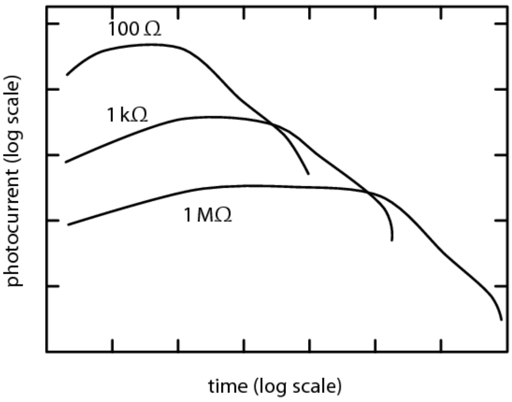


Fig.9.12

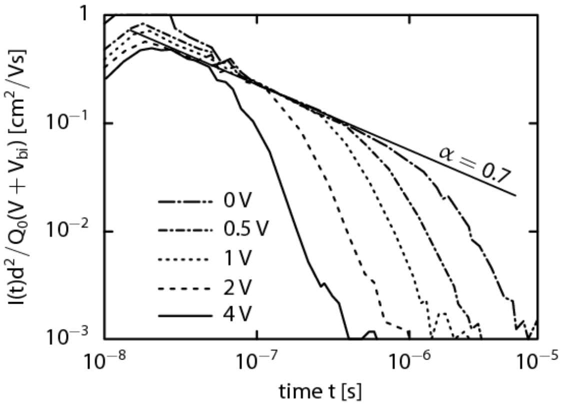


Fig. 9.13

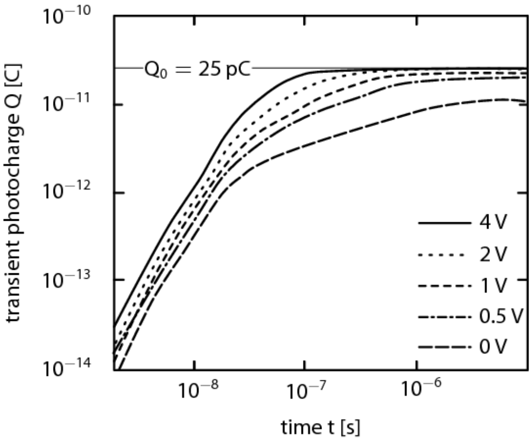


Fig.9.18

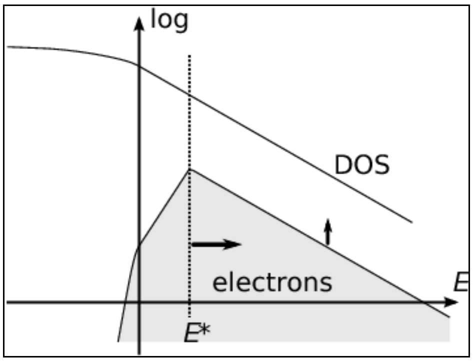
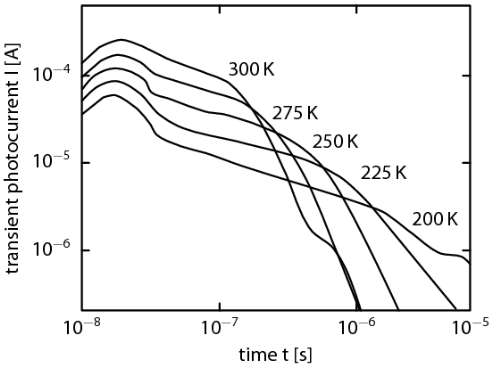


Fig. 9.20



Chapter 11:

p. 287, line 6 from bottom: "SNOM (scanning near field microscopy)" → "SNOM (scanning near field optical microscopy)"

Chapter 12:

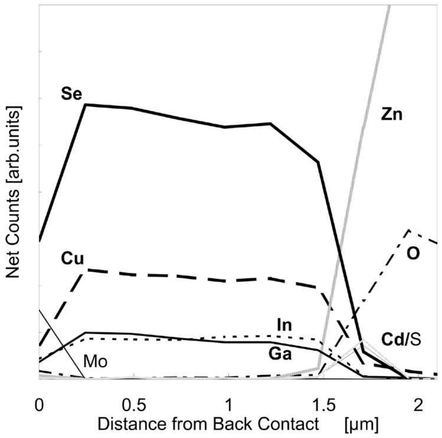
p. 318, title of subsection 12.2.6: “Scanning Probe and Scanning-Probe Microscopy Integrated Platform” → “Scanning Electron and Scanning-Probe Microscopy Integrated Platform”

p. 337, Fig. 12.26, label in lower right-hand diagram should read “Σ3” instead of “f^3”

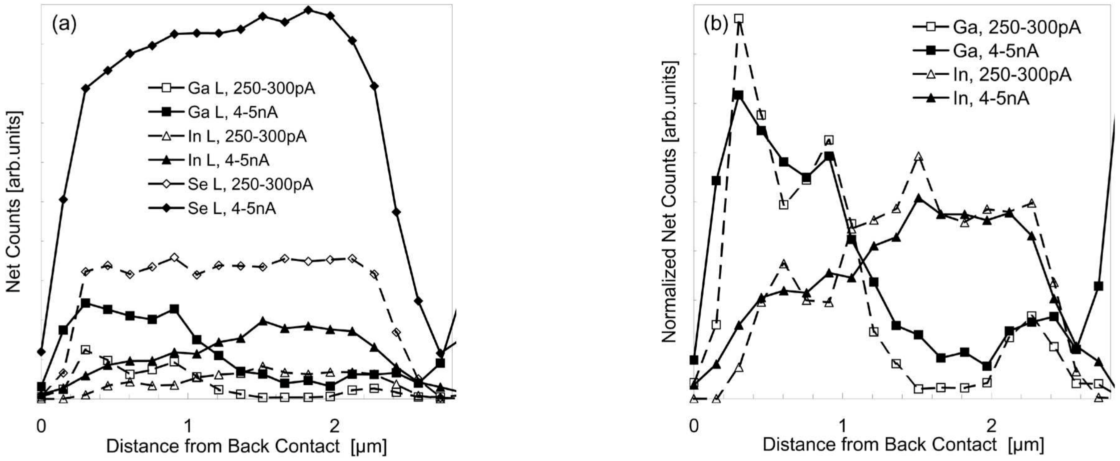
Chapter 16:

p. 418, line 7 above fig. 16.4.: “Figure 16.4 shows a system of Si layers on and SiC substrate” →“Figure 16.4 shows a system of Si layers on a SiC substrate”

p. 441, Fig. 16.21: The correct axis titles are as follows:



p. 444, Figs. 16.24a and b: The correct axis titles are as follows:



Chapter 17:

p. 458, 3 lines from bottom: “with an atomic diameter“ → "with a molecular diameter"
p. 464, citation in caption of Fig. 17.8: this figure is not taken from [31] Anderson and Stuart, but from Norton, J.F. (1953) Helium diffusion through glass. Journal of the American Ceramic Society, 36, 90-96 [31 a].

Chapter 19:

p. 510, Table 19.1: The entries highlighted by red background were not in the correct lines in the printed book.

Process		**Rate**
electron capture	r_1	$nv_{\mathrm{th}}\sigma_{\mathrm{n}}^{+}N_{\mathrm{DB}}F^{+}$
electron emission	r_2	$e_{\mathrm{n}}^{0}N_{\mathrm{DB}}F^{0}$
hole capture	r_3	$nv_{\mathrm{th}}\sigma_{\mathrm{n}}^{0}N_{\mathrm{DB}}F^{0} \rightarrow pv_{\mathrm{th}}\sigma_{\mathrm{p}}^{0}N_{\mathrm{DB}}F^{0}$
hole emission	r_4	$e_{\mathrm{n}}^{-}N_{\mathrm{DB}}F^{-} \rightarrow e_{\mathrm{p}}N_{\mathrm{DB}}F^{+}$
electron capture	r_5	$pv_{\mathrm{th}}\sigma_{\mathrm{p}}^{0}N_{\mathrm{DB}}F^{0} \rightarrow nv_{\mathrm{th}}\sigma_{\mathrm{n}}^{0}N_{\mathrm{DB}}F^{0}$
electron emission	r_6	$e_{\mathrm{p}}N_{\mathrm{DB}}F^{+} \rightarrow e_{\mathrm{n}}^{-}N_{\mathrm{DB}}F^{-}$
hole capture	r_7	$pv_{\mathrm{th}}\sigma_{\mathrm{p}}^{-}N_{\mathrm{DB}}F^{-}$
hole emission	r_8	$e_{\mathrm{p}}N_{\mathrm{DB}}F^{0}$